



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Yasuhiro OMURA et al.

Group Art Unit: 2873

Application No.: 10/525,372

Examiner: M. HASAN

Filed: February 23, 2005

Docket No.: 122800

For: PROJECTION OPTICAL SYSTEM AND METHOD FOR PHOTOLITHOGRAPHY
AND EXPOSURE APPARATUS AND METHOD USING SAME

REQUEST FOR RECONSIDERATION

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In reply to the June 28, 2007 Office Action, the shortened statutory period for reply
being extended by the attached Petition for Extension of Time, Applicants request
reconsideration of this application in view of the following remarks.